

# Establishing Hardware Outgassing Certification Criteria

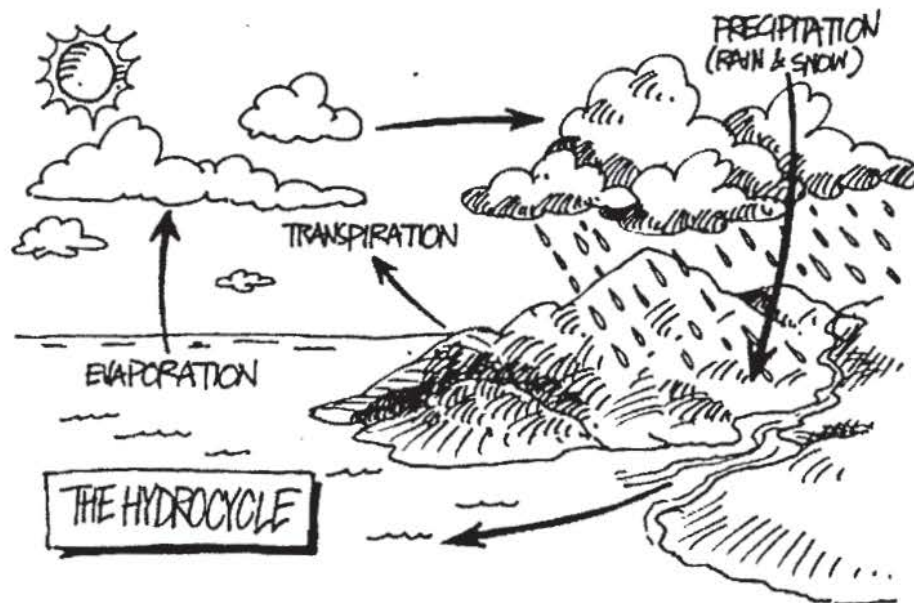
David Hughes

Code 546



# Hardware Requirements

- The QCM measures deposition rate at a particular location in the chamber
  - Chamber modeling is used to determine the deposition rate that results from the desired outgassing rate
  - Specify hardware and QCM temperatures
  - Specify QCM location and orientation



*Just as measuring rainfall in Greenbelt does not tell you the how much water evaporated from the ocean, QCM deposition alone does not tell us the outgassing rate of hardware.*

# Outgassing and Deposition

- Definition

- Outgassing rate (OGR) in g/cm<sup>2</sup>/s to Deposition Rate (DPR) in g/cm<sup>2</sup>/s
  - A is area in cm<sup>2</sup>
  - VF is viewfactor
  - Subscript HW for hardware

$$\frac{OGR_{HW} \cdot A_{HW} \cdot VF_{HW \rightarrow QCM}}{A_{QCM}} = DPR_{QCM}$$

- Deposition rate (g/cm<sup>2</sup>/s) to Delta (Hz/hr)
  - CF is conversion factor from QCM manufacturer (g/cm<sup>2</sup>/Hz)

$$DPR_{QCM} \div CF \cdot \left(3600 \frac{s}{hr}\right) = Delta$$

# Derivation

- Hardware Outgassing
  - Outgassing requirement
    - Derived from the project performance specifications
    - Contaminant effects are used to deduce accretion limits
    - Molecular transport modeling of the spacecraft provides outgassing rate limits that result in acceptable accretions on sensitive surfaces
  - Bakeout requirement (deposition on QCM)
    - Outgassing requirement
    - Chamber configuration
    - Transport modeling of the chamber provides the correspondence between outgassing and deposition

# Background Levels

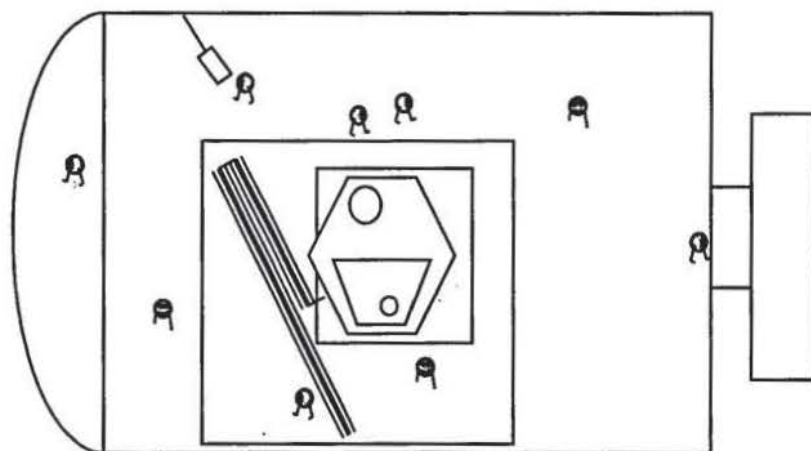
- Background Outgassing

*If the background is high, it is likely to decrease over the course of the hardware test, making data interpretation difficult.*

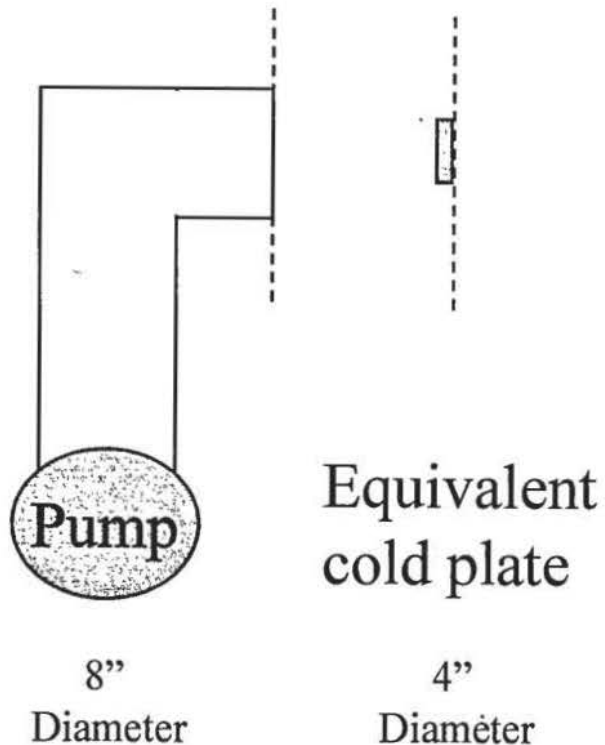
- Chamber history
  - Presence of undesirable species (eg, silicones)
  - High background outgassing rates
- Acceptable background rate
  - Rule of thumb (non-critical): half the hardware requirement
  - Rule of thumb (critical): 1/10<sup>th</sup> the hardware requirement
  - High backgrounds also mean that the coldfinger results are less representative of the hardware being tested
- Pre-test chamber bakeouts are used to reduce the background

# Molecular Transport

- At low pressures, most collisions are with chamber or hardware surfaces, not other molecules
- Molecules do not bounce like balls; they stick to the surface momentarily and then re-emit in a random direction
- Molecules move randomly until they condense on a cold surface
- They do not know where the QCM and pump are located (cold surfaces act like fly paper, not like magnets)



# Effective Pump Area



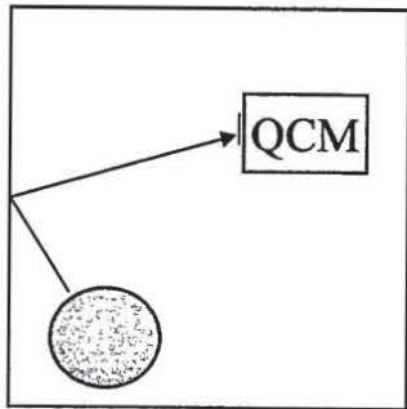
- The vacuum pump is located at the end of a tube, so does not have 100% efficiency
  - Molecules entering the tube can bounce back out
- The pump effective area is the area of a cold plate that would remove molecules at the same rate as the pump
  - Even for simple cases, the chamber pump efficiency must be known
  - The efficiency may be calculated by modeling the pump and chamber, or by running a characterization test

# Viewfactors

- Complex test configurations
  - Multiple hardware elements in view of QCM
  - Non-isothermal environment
  - Numerical analysis is required
- Ideal chamber configurations
  - Viewfactor to the QCM is nearly independent of hardware geometry
- Simple test configurations
  - Isothermal environment
  - Single hardware element
  - Viewfactor may be found statistically

# Geometry Independent

- Ideal “Hot Wall”
- The chamber is sealed
- Only the QCM crystal is cold enough to condense the outgassed species
- The hardware and chamber are the same temperature

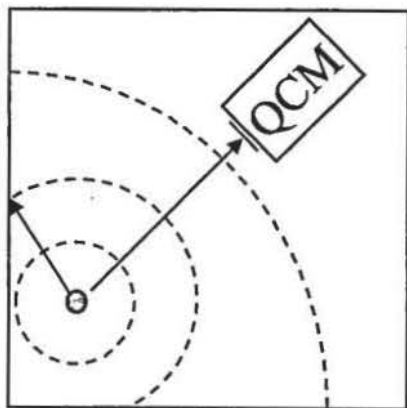


$$VF_{HW \rightarrow QCM} = 1$$

# Configuration

- Ideal “Cold Wall”

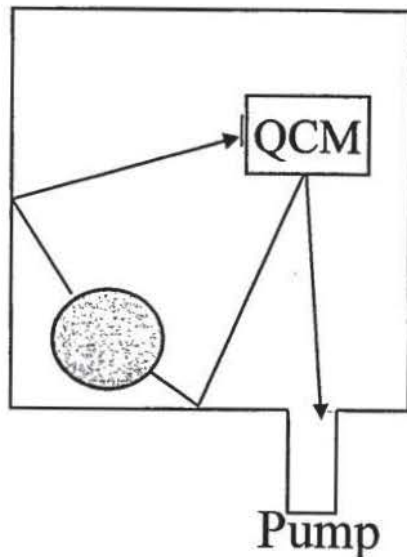
- The hardware is a point source
- All surfaces condense the outgassed species
- Molecules outgas as expanding sphere
- QCM crystal plane is tangent to the sphere



$$VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{4\pi \cdot d_{HW \rightarrow QCM}^2}$$

# Simple Configurations

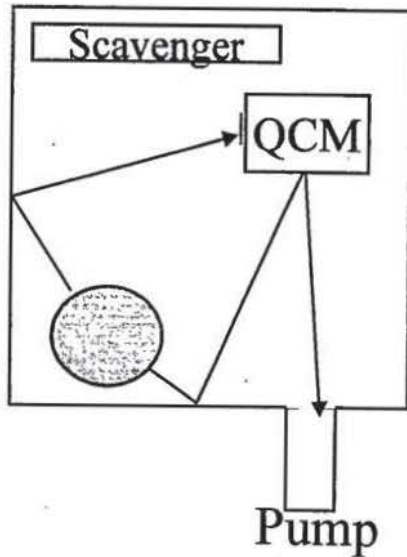
- Hot Wall
  - Chamber and hardware are isothermal
  - Cold surfaces and pump effective area are small (or baffled)
    - When molecules are well mixed (many bounces) before reaching a cold surface, the ratio of areas gives the statistical viewfactor



$$VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{A_{QCM} + A_{Pump} + A_{Other}}$$

# Effective Pump Area

- Hot Wall
  - Chamber Characterization



$$VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{A_{QCM} + A_{Pump} + A_{Other}}$$

$$\frac{OGR_{HW} \cdot A_{HW} \cdot VF_{HW \rightarrow QCM}}{A_{QCM}} = DPR_{QCM}$$

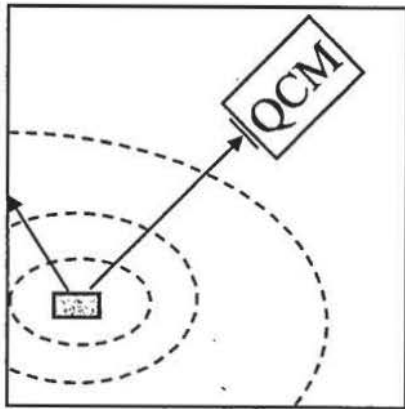
- Solve for unknowns:  $OGR_{chamber}$ ,  $A_{pump}$ 
  - Two equations required
    - Achieve a stable QCM reading
    - Then activate the cold finger or scavenger plate
- Pump effective area is a function of the ratio of before and after rates

$$\frac{Rate_{NoScavenger}}{Rate_{WithScavenger}} = \frac{A_{QCM} + A_{Pump} + A_{Scavenger}}{A_{QCM} + A_{Pump}}$$

$$A_{Pump} \approx \frac{A_{Scavenger}}{Ratio - 1}$$

# Simple Configurations

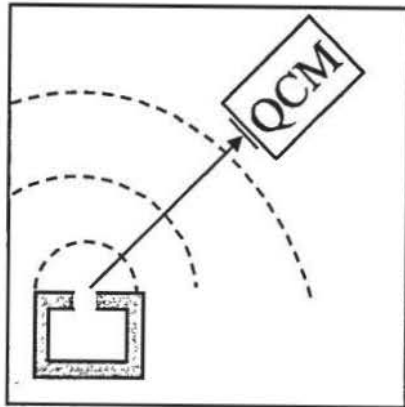
- Cold Wall



- Chamber wall is colder than the QCM
- The hardware item is relatively uniform
  - No vents, lubricated mechanisms, etc
- Item is either small (size  $<$  distance to QCM) or has a simple shape
  - Small items can use the ideal formula
  - Radiation viewfactor formulas have been tabulated for simple shapes (plate to plate, cylinder to plate, etc)

# Simple Configurations

- Cold Wall, Vented Cavity



- Chamber wall is colder than the QCM
- Primary outgassing source is inside a cavity with one vent
- The QCM faces the vent
- Vent is small enough to treat as a point source
  - Diameter  $\ll$  distance to QCM
- Assume molecules exiting the vent are uniformly distributed over a hemisphere
  - Not the end of a tube

$$VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{2\pi \cdot d_{HW \rightarrow QCM}^2}$$

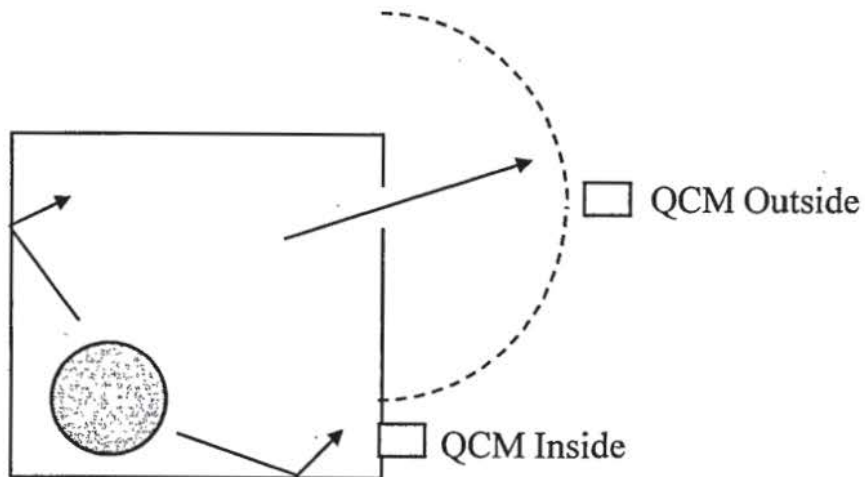
# Test Boxes

- Description
  - We may create a near ideal situation by using an enclosure around the hardware
  - Test box may be much cleaner than the chamber
  - Specify that a test box is required in the test plan
    - Test phases may incorporate changing the vent area
    - Test box may have a coldfinger installed inside

# Test Boxes

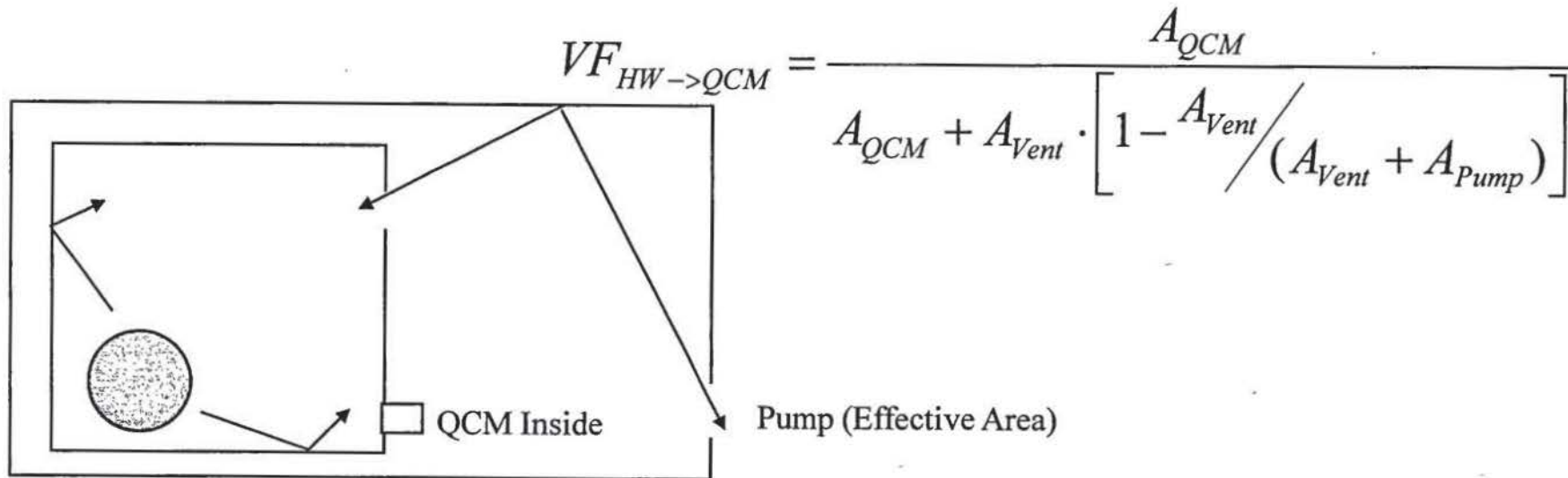
- Test Box w/ Cold Wall

- QCM inside the box
  - Hot Wall equation applies
  - Use the box vent area as the chamber pump area
- QCM outside the box
  - Vented Cavity equation applies



# Test Boxes

- Test Box w/ Hot Wall
- QCM must be inside the box
  - Adjustment of Hot Wall equation
- Random walk causes some molecules to re-enter the box
  - The portion re-entering is  $A_{vent}/(A_{pump}+A_{vent})$
  - This fraction is used to reduce the effective area of the vent



# Viewfactor Summary

- Hot Wall  $VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{A_{QCM} + A_{Pump} + A_{Other}}$

- Ideal Cold Wall  $VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{4\pi \cdot d_{HW \rightarrow QCM}^2}$

- Vented Cavity  $VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{2\pi \cdot d_{HW \rightarrow QCM}^2}$

- Test Box, Hot Wall  $VF_{HW \rightarrow QCM} = \frac{A_{QCM}}{A_{QCM} + A_{Vent} \cdot \left[ 1 - \frac{A_{Vent}}{A_{Vent} + A_{Pump}} \right]}$

$$\frac{OGR_{HW} \cdot A_{HW} \cdot VF_{HW \rightarrow QCM}}{A_{QCM}} = DPR_{QCM}$$